



I. MEMS & Sensor Systems 분과

2019년 2월 15일(금), 11:00-12:30

Room J (란실, 5층)

[FJ2-I] Advanced MEMS and Sensor Systems

좌장: 유경식 교수(KAIST)

<p>FJ2-I-1 11:00-11:30</p>	<p>[초청] Heterogeneous Integration Technology for 3D OEIC Sanghyeon Kim^{1,2} ¹KIST, ²School of Electrical Engineering, KAIST</p>
<p>FJ2-I-2 11:30-11:45</p>	<p>Capacitive Type MEMS Microphone Development Using Lumped Parameter Modeling 정민현¹, 이한춘¹, 이주현¹, 정성경¹, 박동춘¹, 김대영¹, 선종원¹, 이진형¹, 나예은¹, 권혁인¹, 김민성¹, 신금재², 이윤종¹ ¹DB하이텍 기술개발실, ²한국생산기술원</p>
<p>FJ2-I-3 11:45-12:00</p>	<p>Investigation on the Multi-Physical Properties of an Interfacial Layer between a-Si and TiN for Micro-Bolometer Applications Wan-Gyu Lee and Ho-Seung Jeon Korea Department of Global Nanotechnology Development, National NanoFab Center</p>
<p>FJ2-I-4 12:00-12:15</p>	<p>Optimization of Silicon Nanowire ISFET Sensor for Sensitive Detection of Fluoride Ion Hyeon-Tak Kwak¹, Hyeonsu Cho², Kihyun Kim², and Chang-Ki Baek² ¹Department of Electrical Engineering, ²Department of Creative IT Engineering, POSTECH</p>
<p>FJ2-I-5 12:15-12:30</p>	<p>Flexible 99% semiconducting carbon nanotube network transistors for hydrogen sensor application Hyo-Jin Kim¹, Bongsik Choi¹, Jinsu Yoon¹, Yongwoo Lee¹, Min-Ho Kang², Dong Myong Kim¹, Dae Hwan Kim¹, and Sung-Jin Choi¹ ¹School of Electrical Engineering, Kookmin University, ²Department of Nano-process, NNFC</p>